



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Confirmation No.: 2221

Myounggoo LEE et al.

Group Art Unit: 1753

Application No.: 10/658,460

Examiner: Steven H. VERSTEEG

Filed: September 10, 2003

Attorney Docket No.: 101136-00095

For: BIAS SPUTTERING FILM FORMING PROCESS AND BIAS SPUTTERING FILM FORMING APPARATUS

RESPONSE UNDER 37 C.F.R § 1.114

Mail Stop: RCE

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

April 11, 2006

Sir:

This paper is submitted concurrently with a Request for Continued Examination, in reply to the outstanding Final Office Action dated October 11, 2005. The period for response is extended three months, from January 11, 2006, to April 11, 2006, by the attached Petition for Extension of Time. Please amend the application as shown on the following pages:

Amendments to the Claims begin on page 2; and

the **Remarks** begin on page 4.